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**JUL 31 2008**

U.S. Patent Application Serial No. 10/565,156  
Response to OA dated May 12, 2008

**AMENDMENTS TO THE TITLE:**

Please amend the title to read as follows:

**BIMETALLIC PROBE WITH TIP END**

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**AMENDMENTS TO THE SPECIFICATION:**

Please amend the paragraph beginning on page 5, line 14 as follows:

Fig. 1 is a schematic sectional view showing ~~a contact part~~ of a probe according to Embodiment 1 of the present invention;

Fig. 2 is a schematic sectional view showing a state in which ~~the contact part~~ of the probe scrubs an electrode;

Fig. 3 is a schematic sectional view showing a variation in design ~~of the contact part~~ of the probe;

Fig. 4 is a schematic sectional view showing ~~a contact part~~ of a probe according to Embodiment 2 of the present invention;

Fig. 5 is a schematic sectional view showing a state in which ~~the contact part~~ of the probe scrubs an electrode; and

Fig. 6 is a schematic sectional view showing a variation in design ~~of the contact part~~ of the probe, in which (a) is a schematic sectional view showing a case in which an arc-shaped deformation part is provided, and (b) is a schematic sectional view showing a case in which a triangle pyramid-shaped deformation part is provided.

Please amend the paragraph beginning on page 6, line 18, as follows:

First, a probe according to Embodiment 1 of the present invention will be described with reference to the drawings. Fig. 1 is a schematic sectional view showing ~~a contact part~~ of the probe

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according to Embodiment 1 of the present invention, Fig. 2 is a schematic sectional view showing a state in which ~~the contact part of the probe~~ scrubs an electrode, and Fig. 3 is a schematic sectional view showing a variation in design of the contact part of the probe.

Please amend the paragraph beginning on page 7, line 4 as follows:

A probe 100 shown in Fig. 1 comprises a base end 120 ~~(not shown)~~ provided on a substrate which constitutes a probe card, and a columnar contact part 110 which is connected to the base end 120 and can come in contact with an electrode 10 of an object to be measured almost perpendicularly. Herein, the base end 120 may have any shape.

Please amend the paragraph beginning on page 10, line 17, as follows:

A probe according to Embodiment 2 of the present invention will be described with reference to the drawings. Fig. 4 is a schematic sectional view showing ~~a contact part of the probe~~ according to Embodiment 2 of the present invention, Fig. 5 is a schematic sectional view showing a state in which ~~the contact part of the probe~~ scrubs an electrode, and Fig. 6 shows a variation in design of ~~the contact part of the probe~~, in which (a) is a schematic sectional view in which an arc-shaped deformation part is provided and (b) is a schematic sectional view in which a triangular pyramid-shaped deformation part is provided.

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Please amend the paragraph beginning on page 11, line 3 as follows:

A probe 200 shown in Fig. 4 comprises a base end 220 ~~(not shown)~~ provided on a substrate which constitutes a probe card, and a columnar contact part 210 which is connected to the base end 220 and can come in contact with an electrode 10 of an object to be measured almost perpendicularly. In addition, the base end 220 may have any shape.